



PATENT
Docket No.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Scherer et.al.

Examiner: R. McDonald

Serial No: 10/068,283

Art Unit: 1753

Filed: February 5, 2002

Title: DRY ETCHING AND MIRROR
DEPOSITION PROCESSES
FOR SILICONE ELASTOMER

Date: May 14, 2004

CERTIFICATE OF MAILING VIA FIRST CLASS MAIL

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Date of Deposit: May 14, 2004

I hereby certify that the following documents as identified below are being deposited with the United States Postal Service with sufficient postage for first class mail in an envelope addressed to: Mail Stop _____, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450:

1. Correction of Amendment

The above-identified document is enclosed herewith.

Respectfully submitted,

Date: May 14, 2004

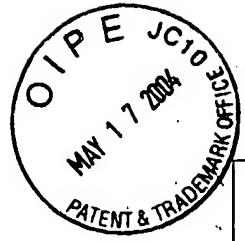
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1753

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re application of:
Scherer et.al.

Serial No.: 10/068,283

Filed: Feb. 5, 2002

For: Dry Etching and Mirror
Deposition Processes for Silicone
Elastomer

Examiner: R.McDonald
Group Art Unit: 1753

CORRECTION OF AMENDMENT

Hon. Commissioner of Patents and Trademarks
Washington DC 20231

Sir:

In reply to the Notice of April 26, 2004 please replace the amendments
to the claims with the appended section.